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## **CLAIMS**

## What is claimed is:

| 1 | 1.              | A dynamic random access memory device comprising:                              |  |
|---|-----------------|--|--|
| 2 |                 | a storage trench;  |  |
| 3 |                 | a storage conductor within said storage trench;                                |  |
| 4 |                 | a lip strap connected to said storage conductor; and                           |  |
| 5 |                 | a control device electrically connected to said storage conductor through      |  |
| 6 | said lip strap. |  |  |
|   |                 |  |  |
| 1 | 2.              | The device in claim 1, wherein said trench has a corner adjacent said          |  |
| 2 | contro          | l device and said lip strap comprises a conductor surrounding said corner.     |  |
|   |                 |  |  |
| 1 | 3.              | The device in claim 1, wherein said control device includes a control          |  |
| 2 | device          | conductive region adjacent said trench and said lip strap comprises a          |  |
| 3 | conduc          | ctor extending along a side of said trench and along a portion of said control |  |

4. The device in claim 1, further comprising a collar insulator along a top portion of said trench, wherein said lip strap comprises a conductor extending from a top of said collar to a top of said trench, said lip strap further extending

device conductive region.

| 4 | along   | along a surface of said device adjacent said trench and perpendicular to said     |  |  |
|---|---------|---|--|--|
| 5 | trencl  | trench.   |  |  |
|   |         | ,   |  |  |
| 1 | 5.      | The device in claim 4, further comprising a node dielectric lining said           |  |  |
| 2 | trench  | trench, wherein said lip strap surrounds an upper portion of said node dielectric |  |  |
| 3 | adjace  | adjacent said top portion of said trench.   |  |  |
|   |         |   |  |  |
| 1 | 6.      | The device in claim 1, further comprising a trench top oxide, wherein said        |  |  |
| 2 | lip str | ip strap extends into said trench top oxide and forms an inverted U-shaped        |  |  |
| 3 | struct  | structure.  |  |  |
|   |         |   |  |  |
| 1 | 7.      | The device in claim 1, wherein said lip strap comprises a conductor               |  |  |
| 2 | extend  | ding along two perpendicular portions of a top corner of said trench.             |  |  |
|   |         |   |  |  |
| 1 | 8.      | A method of forming a dynamic random access memory structure, said                |  |  |
| 2 | metho   | method comprising:  |  |  |
| 3 |         | forming a trench within a substrate;  |  |  |
| 4 |         | filling said trench with a trench conductor;                                      |  |  |
| 5 |         | forming a pad oxide along a surface of said substrate adjacent said trench;       |  |  |
| 6 |         | forming a collar along an upper portion of said trench such that said collar      |  |  |
| 7 | insulat | insulates said substrate from said trench conductor;                              |  |  |
| R |         | recessing said collar and said rad axida.   |  |  |

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| 9  | depositing a lip strap over said trench conductor and in recesses produced |
|----|--|
| 10 | by said recessing; and   |

forming an isolation region adjacent said lip strap.

- 9. The method in claim 8, further comprising forming a control device adjacent said trench, wherein said trench has a corner adjacent said control device and said lip strap comprises a conductor surrounding said corner.
  - 10. The method in claim 8, wherein said forming of said control device includes forming a control device conductive region adjacent said trench and said lip strap comprises a conductor formed along a side of said trench and along a portion of said control device conductive region.
    - 11. The method in claim 8, further comprising forming a collar insulator along a top portion of said trench, wherein said lip strap comprises a conductor formed to extend from a top of said collar to a top of said trench, said lip strap further extending along a surface of said device adjacent said trench and perpendicular to said trench.
- 12. The method in claim 11, further comprising lining said trench with a node dielectric, wherein said lip strap surrounds an upper portion of said node dielectric adjacent said top portion of said trench.

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| 1  | 13.    | The method in claim 8, further comprising forming a trench top oxide,               |  |  |
|----|--------|---|--|--|
| 2  | such t | such that said lip strap extends into said trench top oxide and forms an inverted U |  |  |
| 3  | shape  | shaped structure.   |  |  |
|    |        |   |  |  |
| 1  | 14.    | The method in claim 8, wherein said lip strap comprises a conductor                 |  |  |
| 2  | forme  | ed along two perpendicular portions of a top corner of said trench.                 |  |  |
|    |        |   |  |  |
| 1  | 15.    | A method of forming a dynamic random access memory structure, said                  |  |  |
| 2  | metho  | method comprising:  |  |  |
| 3  |        | forming a trench within a substrate;  |  |  |
| 4  |        | filling said trench with a trench conductor;  |  |  |
| 5  |        | forming a pad oxide along a surface of said substrate adjacent said trench;         |  |  |
| 6  |        | forming a collar along and upper portion of said trench such that said              |  |  |
| 7  | collar | collar insulates said substrate from said trench conductor;                         |  |  |
| 8  |        | forming an isolation region adjacent said trench conductor;                         |  |  |
| 9  |        | recessing said collar and said pad oxide; and                                       |  |  |
| 10 |        | depositing a lip strap over said trench conductor and in recesses produced          |  |  |
| 11 | by sai | d recessing.  |  |  |
|    |        |   |  |  |
| 1  | 16.    | The method in claim 15, further comprising forming a control device                 |  |  |

adjacent said trench, wherein said trench has a corner adjacent said control device

and said lip strap comprises a conductor surrounding said corner.

- 1 17. The method in claim 15, wherein said forming of said control device
  2 includes forming a control device conductive region adjacent said trench and said
  3 lip strap comprises a conductor formed along a side of said trench and along a

  portion of said control device conductive region.
  - 18. The method in claim 15, further comprising forming a collar insulator along a top portion of said trench, wherein said lip strap comprises a conductor formed to extend from a top of said collar to a top of said trench, said lip strap further extending along a surface of said device adjacent said trench and perpendicular to said trench:
  - 19. The method in claim 11, further comprising lining said trench with a node dielectric, wherein said lip strap surrounds an upper portion of said node dielectric adjacent said top portion of said trench.
  - 20. The method in claim 15, further comprising forming a trench top oxide, such that said lip strap extends into said trench top oxide and forms an inverted U-shaped structure.